

       	<b>US4785177</b> <b>Biblio</b> <b>Desc</b> <b>Claims</b> <b>Page 1</b> <b>Drawing</b> <b>esp@cenet</b>
<b>Kinematic arrangement for the micro-movements of objects</b>	
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<hr/> <b>Abstract</b> <hr/>	
<p>A kinematic arrangement for the micro-movement over long distances of objects, and in particular, for imparting movement to and the manipulation of objects which are to be investigated or treated microscopically. The object is supported on at least one motion-imparting or kinematic element constituted of piezoelectric material, which is deformable through the application of electrical voltages. The supporting point or points of the kinematic or motion-imparting elements is or are changed in position through a deformation of the piezoelectric material due to the application of electrical voltage variations to the kinematic element, which so changes in its position that the object which is supported by the kinematic elements will move in desired directions within a plane predetermined by the supporting points.</p>	
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